

Young Bong Shin

List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/4122149/publications.pdf>

Version: 2024-02-01

17
papers

129
citations

1307594

7
h-index

1281871

11
g-index

17
all docs

17
docs citations

17
times ranked

97
citing authors

#	ARTICLE	IF	CITATIONS
1	Oxygen partial pressure and thermal annealing dependent properties of RF magnetron sputtered TiO _{2-x} films. Materials Science in Semiconductor Processing, 2015, 32, 107-116.	4.0	20
2	Bolometric properties of reactively sputtered TiO _{2-x} films for thermal infrared image sensors. Journal Physics D: Applied Physics, 2015, 48, 355104.	2.8	18
3	Enhanced bolometric properties of TiO _{2-x} thin films by thermal annealing. Applied Physics Letters, 2015, 107, .	3.3	18
4	Substrate temperature dependent bolometric properties of TiO _{2-x} films for infrared image sensor applications. Ceramics International, 2016, 42, 17123-17127.	4.8	14
5	Effect of sputtering pressure on microstructure and bolometric properties of Nb:TiO _{2-x} films for infrared image sensor applications. Journal of Applied Physics, 2016, 119, .	2.5	12
6	Nb doping effect on TiO _{2-x} films for bolometer applications. Journal of Physics and Chemistry of Solids, 2016, 91, 128-135.	4.0	9
7	Systematic Investigation on Deposition Temperature Effect of Ni _{1-x} O Thin Films for Uncooled Infrared Image Sensor Applications. IEEE Sensors Journal, 2015, 15, 7234-7241.	4.7	7
8	Anodic Aluminum Oxide-Based IR Emitter for High-Speed Infrared Scene Projector. Journal of Microelectromechanical Systems, 2019, 28, 1032-1038.	2.5	7
9	Bolometric properties of oxygen atmosphere annealed Nb:TiO _{2-x} films for infrared detectors. Ceramics International, 2017, 43, 9207-9213.	4.8	5
10	Improvement of the thermal stability of Nb:TiO _{2-x} samples for uncooled infrared detectors. Journal Physics D: Applied Physics, 2018, 51, 025104.	2.8	5
11	Sputtering pressure dependent bolometric properties of Ni _{1-x} O thin films for uncooled bolometer applications. Ceramics International, 2017, 43, 9498-9504.	4.8	4
12	Enhanced bolometric properties of nickel oxide thin films for infrared image sensor applications by substitutional incorporation of Li. Ceramics International, 2018, 44, 7808-7813.	4.8	4
13	Influence of passivation layer on thermal stability of Nb:TiO _{2-x} samples for shutter-less infrared image sensors. Infrared Physics and Technology, 2019, 100, 52-56.	2.9	3
14	Influence of Nb Doping Concentration on Bolometric Properties of RF Magnetron Sputtered Nb:TiO _{2-x} Films. Journal of Electronic Materials, 2018, 47, 2171-2176.	2.2	2
15	Residual stress analysis of anodic aluminum oxide thin films for infrared emitter device application.. , 2019, , .		1
16	Influence of deposition temperature on TiO _{2-x} films for infrared image sensor applications: TiO _{2-x} films: Infrared image sensor applications. , 2015, , .		0
17	Oxygen Atmosphere Annealing Effect on the Thermal Stability of TiO _{2-x} Based Films for Shutter-Less Infrared Image Sensors. Key Engineering Materials, 0, 775, 272-277.	0.4	0